

Session Title:	[WF1] Diagnosis for Plasma Process
Session Date:	November 16 (Wed.), 2022
Session Time:	10:45-11:55
Session Room:	Room F (Sicily Room, 1F)
Session Chair:	Prof. Sang Jeon Hong (Myungji Univ., Korea)

[WF1-1] [Invited] 10:45-11:15

PI-VM: The Most Efficient Way to Control the Plasma Processes in Mass Production with Data-Driven Plasma Science

Seolhye Park, Jaegu Seong, Yoona Park, and Gon-Ho Kim (Samsung Display Co., Ltd., Korea)

[WF1-2] 11:15-11:35

Semiconductor Plasma Process/Equipment Diagnosis Research for the Last Two Decades

Sang Jeon Hong (Myongji Univ., Korea)

[WF1-3] 11:35-11:55

Plasma Sensor for Intelligent Semiconductor/Display Process

H-C Lee, H J Yeom, J H Kim (KRISS, Korea), S J You (Chungnam Nat'l Univ., Korea), K H You, D H Choi, E S Choi, M Y Yoon, and D J Seong (KRISS, Korea)